



Honeywell's Docket No. H0004870 US -4015
Proprietor's Docket No. H9945-1305 (7240122001-3224000)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Mize et al.**

Serial No: **10/542040**

Filed: **July 13, 2005**

For: **Apparatus and Methods
for Ionized Deposition of a
Film or Thin Layer**

Group: **Not Yet Assigned**

Examiner: **Not Yet Assigned**

INFORMATION DISCLOSURE STATEMENT

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ALEXANDRIA, VA 22313-1450

Sir:

In accordance with the duty of disclosure imposed by 37 C.F.R. § 1.56 to inform the United States Patent and Trademark Office of all references coming to the attention of the Applicant(s) or attorneys or agents for Applicant(s) which are or may be material to the examination of the subject application, attorneys for the Applicant(s) hereby invite the Examiner's attention to the references listed in the accompanying PTO Form 1449 entitled "List of References Cited".

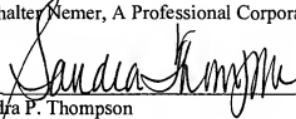
This submission is understood to complement the results of the Examiner's own independent search. The submission of this Disclosure Statement should not be construed as a representation that a search was made, or that the cited items are inclusive of all relevant and material citations that may be available publicly.

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Applicant(s) respectfully request that the Examiner review the foregoing references, as set forth in the Form PTO-1449, and that they be made of record in the file history of the above-captioned application.

Respectfully submitted,

Buchalter Nemer, A Professional Corporation

Dated: October 13, 2005
By: 
Sandra P. Thompson
Reg. No. 46,264

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ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /J.B./^{PSW}

LIST OF REFERENCES CITED BY APPLICANT

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

| *EXAMINER INITIAL | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE |
|-------------------|-----------------|----------|------------------|-------|----------|----------------------------|
| | US 2001/0007302 | 07/12/01 | Hong | 204 | 192.12 | 05/16/97 |
| | US 2001/0019016 | 09/06/01 | Subramani et al. | 204 | 192.1 | 04/10/01 |
| | US 2002/0047116 | 04/25/02 | Pavate et al. | 257 | 44 | 09/28/01 |
| | US 2002/0144901 | 10/10/02 | Nulman et al. | 204 | 298.06 | 01/17/02 |
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FOREIGN PATENT DOCUMENTS

| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION |
|--|--|-----------------|------|---------|-------|----------|-------------|
| | | | | | | | YES NO |
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

| | |
|--|---|
| | PCT International Search Report dated October 26, 2004 |
| | PCT Written Opinion dated October 26, 2004 |
| | PCT International Preliminary Examination Report dated August 4, 2005 |

| | | |
|----------|----------------|-----------------|
| EXAMINER | /Jason Berman/ | DATE CONSIDERED |
| | | 02/05/2009 |

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /J.B./



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Repetition's Docket No. H9945-1305 (7240122001-3224000)

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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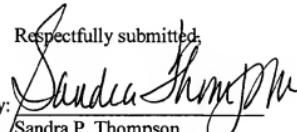
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TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT WITHIN THREE MONTHS OF FILING OR BEFORE MAILING OF FIRST OFFICE ACTION (37 C.F.R. 1.97(b))

IDENTIFICATION OF TIME OF FILING THE ACCOMPANYING INFORMATION DISCLOSURE STATEMENT

The information disclosure statement submitted herewith is being filed within three months of the filing date of the application or date of entry into the national stage of an international application or before the mailing date of a first Office action on the merits, whichever event occurs last. 37 C.F.R. 1.97(b).

Date: October 13, 2005

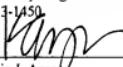
Respectfully submitted,
 By: 
 Sandra P. Thompson
 Reg. No. 46264

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CERTIFICATE OF MAILING (37 C.F.R. 1.8(a))

I hereby certify that, on the date shown below, this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail, in an envelope addressed to the Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450.

Kristin J. Azcuna


 Date: October 13, 2005

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /J.B./